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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if appropriate
QNV		5,696,388	12/09/1997	FUNADA, et al.			

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QNV		7-99314	04/11/1995	JAPAN			Abstract
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QNV		97/45827	12/04/1997	PCT			Yes

OTHER DOCUMENT(S) (*Including Author, Title, Date, Pertinent Pages, etc.*)

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Examiner Signature: Quynh Nhu Vu **Date Considered:** 8/24/01

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant(s).